

## AMENDMENTS TO THE SPECIFICATION

Please amend the title of the application appearing on page 1 of the specification as follows:

~~LARGE TILT ANGLE MEM~~MICROELECTROMECHANICAL SYSTEM FOR  
TILTING A PLATFORM

Please amend the paragraphs beginning on page 8 at line 2 of the specification as follows:

For a more complete understanding of the present invention and further advantages thereof, reference is now made to the following Detailed Description, taken in conjunction with the drawings, in which:

FIG. 1A shows a schematic plan view of a first embodiment of a MEM system in accordance with the present invention;

FIG. 1B shows a schematic side view of the MEM system of FIG. 1A prior to elevation of the platform from the substrate;

FIG. 1C shows a schematic side view of the MEM system of FIG. 1A with the platform elevated from the substrate;

FIG. 1D shows a schematic side view of the MEM system of FIG. 1A with the platform elevated from the substrate and tilted with one degree of freedom;

FIG. 1E shows a schematic side view of the MEM system of FIG. 1A with the platform elevated from the substrate and tilted with two degrees of freedom;

FIG. 1F shows a schematic plan view of an embodiment of a MEM system similar to that shown in FIG. 1A having different length lever arms;

FIG. 2 shows a schematic plan view of a second embodiment of a MEM system in accordance with the present invention;

FIG. 3 shows a schematic plan view of a third embodiment of a MEM system in accordance with the present invention;

FIG. 4 shows a schematic plan view of a fourth embodiment of a MEM system in accordance with the present invention;

~~FIGS. 5A-C~~5A, 5B and 5C show plan and side views of one embodiment of a segmented

torsional spring compliant member in accordance with the present invention;

FIG. 6 shows a schematic plan view of an embodiment of a MEM system in accordance with the present invention configured to provide for more precise control of the platform; and

FIG. 7 shows a schematic plan view of another embodiment of a MEM system in accordance with the present invention wherein the platform is not attached to the substrate.

Please amend the paragraph beginning on page 14, line 23 as follows:

Referring now to FIG. 1F, it should be noted that although in the MEM system 10 illustrated in FIGS. 1A-E, the right and left-side A-frame structures 40, tethers 38, displacement multipliers 34, yokes 32 and actuators 30 are identically configured (e.g., the A-frame structures 40 comprise equal length lever arms), such symmetry is not required where one wants to achieve a particular voltage-to-tilt angle transfer function depending upon, for example, the shape of a target one may want to reflect light to from a reflective surface provided on the platform 14. For example, as is illustrated in FIG. 1F, the lengths of the right and left-side A-frame structures 40 may be different to provide different length lever arms or the tethers 38 can be attached at different locations on right and left-side A-frame structures 40 so that equal applied voltages across the right and left-side pairs of actuators 30 achieves tilting of the platform 14 simultaneously about both axes 50 and 52.